

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: )  
)  
Yasuhiro OMURA ) Present Group Art Unit: 2851  
)  
Application No.: 1.53(b) Continuation of ) Present Examiner: Hung Nguyen  
Application No. 09/865,734 )  
)  
Filed: Herewith )  
)  
For: PROJECTION OPTICAL SYSTEM, )  
EXPOSURE APPARATUS )  
INCORPORATING THIS )  
PROJECTION OPTICAL SYSTEM, )  
AND MANUFACTURING METHOD )  
FOR MICRO DEVICES USING )  
THE EXPOSURE APPARATUS )

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**PRELIMINARY AMENDMENT**

Prior to the examination of the above application, please amend this application  
as follows:

**Amendments to the Specification** are included in this paper beginning on page  
2.

**Amendments to the Claims** are reflected in the listing of claims in this paper  
beginning on page 3.

**Remarks/Arguments** follow the amendment sections of this paper beginning on  
page 14.

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